

Wafer Sorter mWS 200/300



Description

The Wafer Sorter mWS 200/300 is designed for sorting 200/300 mm (8"/12") wafers and can be equipped with up to four cassettes or FOUPs (mixed loading possible).

The mWS 200/300 handles wafers out of a cassette / FOUP onto a pre-aligner, forward onto a visual inspection unit and back into a cassette / FOUP.

Applications

- sorting
- splitting
- merging

Features

- optimized footprint
- highest product & operator safety
- high throughput (up to 201 wafers/h)
- handling of standard and TAIKO wafers
- handling of thin and warped wafers
- Cleanroom class: ISO class 5
- CE certificated
- SEMI standards compliant

Basic Configuration

- one dual-arm robot on linear track
- two Bernoulli vacuum end-effectors for 8" and 12"
- wafer flipping function
- up to four load ports for 8" and 12"
- up to four cassette adapter plates for 8"
- one pre-aligner for 8" and 12"
- GUI

Configuration Options

- RFID reader for FOUP- / cassette-ID
- green light visual inspection
- OCR reader for wafer ID
- camera for handling area monitoring
- SECS/GEM interface
- FFU (filter fan unit) for higher cleanroom class
- UPS (uninterruptible power supply)
- ionizer

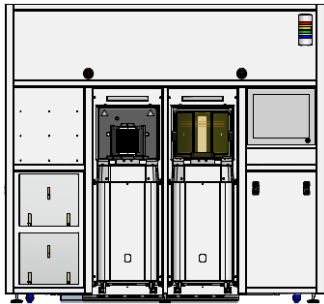
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Wafer Sorter

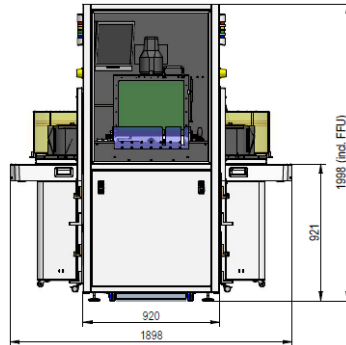
mWS 200/300

Specifications

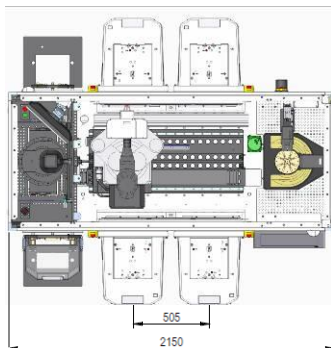
Front view



Left side



Plan view



Wafer size and thickness	200 mm (8"): standard > 175 µm, TAIKO > 40 µm 300 mm (12"): standard > 700 µm, TAIKO > 40 µm
Cleanroom class*	ISO class 5
Noise emission	< 70 dB(A)
Dimensions	
w / d / h in mm	2150 / 1900 / 2000
Weight	About 1160 kg
Operation and loading	
Operation and loading	Front and back side loading / front and left side operation
Cassette / FOUP loading	Manual, OHT (optional)
Supply	
Power supply	200-240 VAC / 50-60 Hz / 16 A
Control voltage	24 VDC
Pneumatic CDA and Vacuum	
Supply CDA	99 l/min at 6.0 – 6.5 bar
Supply vacuum	20 l/min at -80 kPa
Interface	
Operator interface	Touch screen
External interface	USB, Ethernet, SECS/GEM (optional)
Service Interface	Remote control (optional)
Throughput	
CE certificates	Up to 201 wafers per hour (depends on recipe)
CE certificates	2006/95/EC, 2006/42/EC, 2004/108/EC
SEMI standards compliant	

* ISO EN 14 644-1

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